

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

PRIORITY Application Serial No. .... 09/653,157  
PRIORITY Filing Date ..... August 31, 2000  
Inventor..... Kevin J. Torek et al.  
Assignee..... Micron Technology, Inc.  
PRIORITY Group Art Unit..... 1765  
PRIORITY Examiner ..... Deo, Duy Vu Nguyen  
Attorney's Docket No. .... MI22-2559  
Title: Methods of Removing Material from a Semiconductor Substrate (as amended)

**AMENDMENT ACCOMPANYING CONTINUATION APPLICATION FILING**

To: MS Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

**AMENDMENTS**

**Introductory Comments**

The preliminary amendment accompanies filing of a continuation application.  
Applicant amends the application and remarks as follows.